




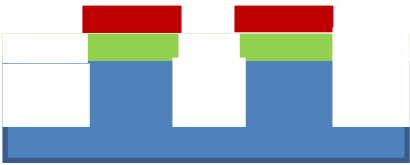








Microchannel Fabrication



Date	Bay	Process	Device cross section
	Wet etch	RCA Cleaning	
	Dry etch	PECVD silicon oxide	
	Inline characterisation	Inspection: thickness measurement	
	Lithography	Patterning	
	Dry etch	Oxide etch	
	Dry etch	Deep silicon etch	
	Dry etch	Resist strip	

	Microfluidics Lab	PDMS mold preparation	
	Microfluidics Lab	PDMS curing and peel	
	Microfluidics Lab	Glass bonding	



silicon



oxide



resist



PDMS



Glass